t Named Inventor Andrei Mihnea 10/636,181 rial No. August 7, 2003 Filing Date Group Art Unit 2818 **Examiner Name** Unknown MAY 1 8 2014 Confirmation No. 1762 & TRADEN Attorney Docket No. 400.237US01

GENERAL TRANSMITTAL FORM UNDER 37 CFR 1.8 (LARGE ENTITY)

Title: METHOD FOR ERASING AN NROM CELL

Mail Stop: AMENDMENT Commissioner for Patents

P. O. Box 1450

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Enclosures

The following documents are enclosed:

- X Information Disclosure Statement (1 pg.); Form 1449 (7 pgs.); 58 copies of cited references; U.S. reference(s) not included pursuant to 37 C.F.R. 1.98 (c)(2)(i);
- <u>X</u> An itemized return-receipt postcard

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Name	Rhonda L. Foley	Signature 😽	nonde L	to ley		

(LARGE ENTITY TRANSMITTAL UNDER 37 CFR § 1.8)

St Named Inventor	Andrei Mihnea	
Serial No.	10/636,181	INFORMATION
Filing Date	August 7, 2003	DISCLOSURE
Group Art Unit	2818 MAY 1 8 2004	STATEMENT
Examiner Name	Unknown	
Confirmation No.	1762	
Attorney Docket No.	400.237US01	
Title: METHOD FOR	ERASING AN NROM CELL	

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In compliance with 37 C.F.R. §§ 1.56 and 1.97, et seq., the enclosed materials are brought to the attention of the Examiner for consideration in connection with the above-identified Application. Pursuant to 37 C.F.R. 1.98 (a)(2)(ik), as this application was filed after June 30, 2003, Applicant has not included copies of U.S. Patents or U.S. Patent Applications. Applicant respectfully requests that this Information Disclosure Statement be entered and the references listed on the attached Form 1449 be considered by the Examiner and made of record. Pursuant to MPEP §609, Applicant further requests that the Examiner initial next to each reference on the Form 1449 to indicate that the listed references have been considered. Applicant further requests that a copy of the initialed Form 1449 be returned with the next official communication.

As an Office Action has not yet issued in this application, Applicant believes that no fees are due. However, the Commissioner for Patents is hereby authorized to charge any additional fees to Deposit Account No. 501373. If the Examiner has any questions or concerns regarding this application, please contact the undersigned at (612) 312-2211.

Respectfully submitted,

Date:

Kenneth W. Bolvin

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Serial No. 10/636,181

Filing Date August 7, 2003

Group Art Unit 2818

Examiner Name Unknown
Confirmation No. 1762

Attorney Docket No. 400.237USO

INFORMATION DISCLOSURE STATEMENT FORM PTO-1449

Title: METHOD FOR ERASING AN NEOM GENEY

Sheet 1 of 7

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First Named Inventor	Andrei Mihnea
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Filing Date	August 7, 2003
Group Art Unit	2818
Examiner Name	Unknown
Confirmation No.	1762
Attorney Docket No.	400.237US01

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Title: METHOD FOR ERASING AN NROM CELL Sheet 3 of 7

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First Named Inventor	Andrei Mihnea	
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Filing Date	August 7, 2003] ''''
Group Art Unit	2818]
Examiner Name	Unknown]
Confirmation No.	1762	
Attorney Docket No.	400.237US01	
	27 - AD 10 - 1313 ID A3 - ADI I	

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